



TS/C-03-222

February 27, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/736,948 12/16/03 |
Chih-Min Tseng et al.
| DRY FILM REMOVE PRE-FILER SYSTEM |
| _____ |

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on March 1, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

SB Ackerman 3/1/04

TSMC-03-222

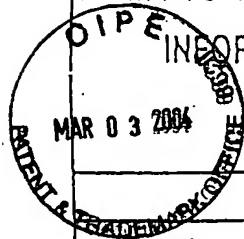
U.S. Patent 5,942,369 to Ota et al., "Positive Photoresist Composition," discloses a positive photoresist composition.

U.S. Patent 4,906,341 to Yamakawa et al., "Method of Manufacturing Semiconductor Device and Apparatus Therefor," discloses a method and apparatus for manufacturing semiconductor devices.

Sincerely,

A handwritten signature in black ink, appearing to be 'SBA', written over the printed name.

Stephen B. Ackerman,
Reg. No. 37761



INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Doctor Number (Specimen)

TSmc-03-222

Application Number

10/736,948

Applicant:

Chih-Min Tseng et al.

Filing Date

12/16/03

Of our 1st year

U. S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

[illegible]

ΕΛΛΗΝΙΣΜ

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.